

# PATENT ABSTRACTS OF JAPAN

(11)Publication number : **10-303286**  
(43)Date of publication of application : **13.11.1998**

(51)Int.Cl. **H01L 21/68**  
**B23Q 3/15**  
**H01L 21/3065**  
**H02N 13/00**

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(30)Priority

Priority number : **09 40836** Priority date : **25.02.1997** Priority country : **JP**

(54) **ELECTROSTATIC CHUCK AND SEMICONDUCTOR MANUFACTURING EQUIPMENT**

(57)Abstract:

PROBLEM TO BE SOLVED: To provide an electrostatic chuck capable of easily taking a measure against corrosion of a surface.

SOLUTION: An electrostatic chuck 26 is fixed on a pedestal 22 in a treating chamber of an etching equipment or the like. The electrostatic chuck 26 is provided with a base 28 composed of dielectric ceramic, an electrode 38 which is arranged on the base 28 with a given pattern, and a surface layer 40 composed of dielectric ceramic which is arranged on the base 28 so as to cover the electrode 38. The base 28 and the surface layer 40 are bonded with adhesive agent in such a manner that exfoliation is possible. By the above structure, only the surface layer 40 of the electrostatic chuck 26 can be quickly exchanged.

